CORRIGENDUM

Consequent upon the Pre-Bid meeting held on 22.11.2023 in reference to Tender IIT(BHU))/MainWorkshop/2023-24/SEM/177, dated 14.11.2023 for Supply, installation, demonstration of SEM, Nanomanipulator & Lithography System at IIT (BHU) Varanasi, the following changes are made in Tender Document.

In this connection, the following amendments may please be noted in the above referred Tender:

S1. No.	Tender document reference	Original Content	Amended content
1	Technical Specification Point No. 17 Page no. 35-36	 The system should contain the newest generation of probes mounted on a load-lock compatible platform with an integrated super-flat three axis substage. Insulation leakage current: <50 fA/V or better. 	 The system should contain the newest generation of probes (minimum 4 probes) mounted on a load-lock compatible platform with an integrated super-flat three axis substage or equivalent. Insulation leakage current: <100 fA/V or better

The remaining content of the Tender will remain unchanged.

Date: 22.11.2023

(CHAIRMAN)